

DEVELOPMENT OF ELECTRONICS DEVICE FABRICATION AND CHARACTERIZATION FACILITY

(Proposed Clean room facility equipped with fabrication and characterization tools)

Funding Agencies:

- ❖ FIST – Department Of Science And Technology, Level-I (Sanctioned Amount: 217 Lakhs)
- ❖ Punjab Engineering College (Deemed to be University) (Sanctioned Amount: 164 Lakhs)

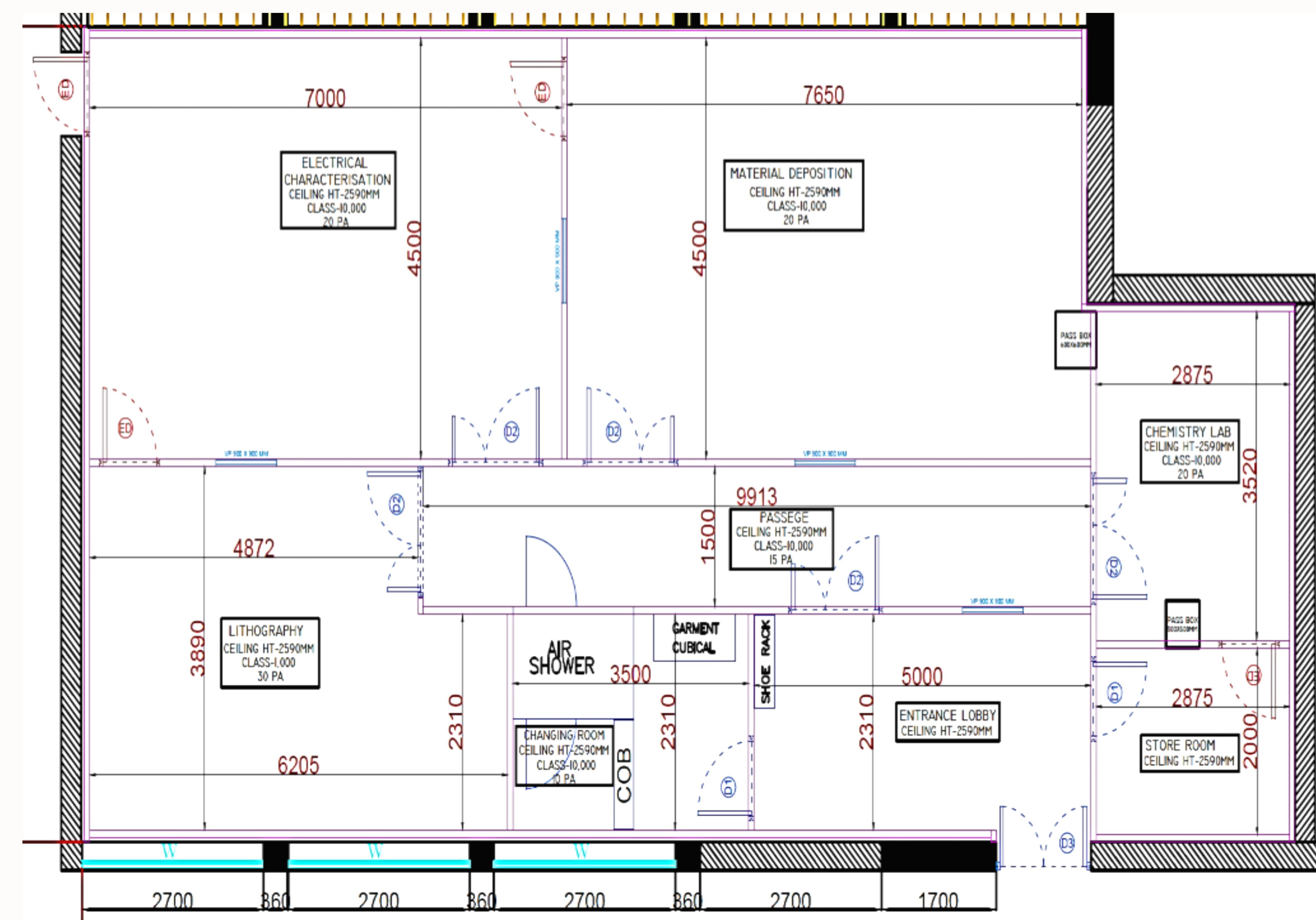
Coordinator: Dr. Arun Kumar Singh (Associate Professor, ECE Dept.)





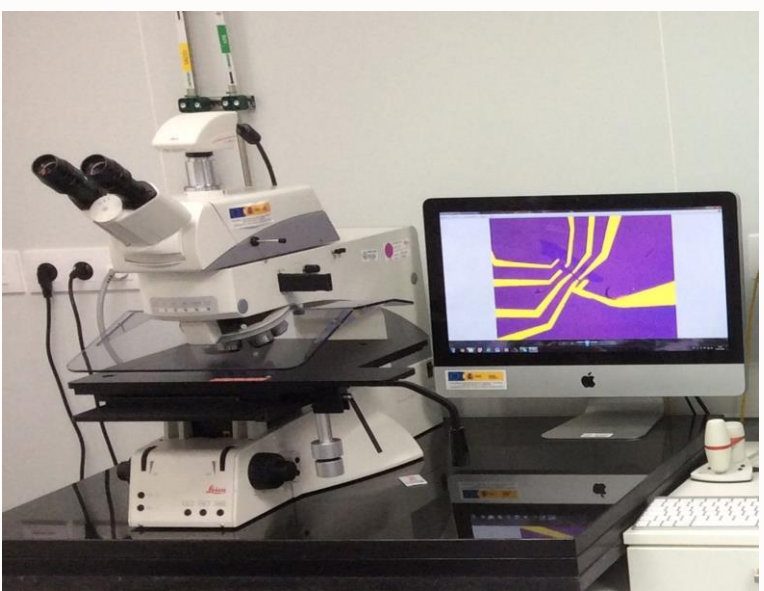


Indicative Images of upcoming Clean Room Facility in ECE Dept.

Clean Room Layout (Tentative)

(Allotted space: Physics Laboratory (Old) adjacent to DTE office)



Equipment to be Procured		Cost (Lakhs)	Applications
Chemical Vapour Deposition (CVD)		35.00	To deposit thin films of various material including Graphene
Mask Aligner		85.00	To write the patterns of contacts and Devices
Reaction Ion Etching (RIE)		45.00	To clean and etch the samples/devices
RF/DC Sputter System		23.00	To Deposit thin films of Oxide materials/ metals
Optical Microscope with image capturing		13.00	To investigate/capture images of device/samples